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**VEADED** Substitute for form 1449B/PTO Complete if Known 10/757973 **Application Number** INFORMATION DISCLOSURE

STATEMENT BY APPLICANT				Filing Date	01/13/2004		
	Data Culturilla	Sads lisma 20	2005	First Named Inventor	Jun XIE		
	Date Submitte	8a: June Sc	), 2005	Group Art Unit	3746		
	(use as many s	heets as ne	cessary)	Examiner Name	Charles G. Freay		
Sheet	1	of	1	Attorney Docket Number	049411-0253		
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Examiner Initials*		U.S. Patent	Document	Name of Patentee or Applicant of Cited Document	Date of Publication of	Pages, Columns, Lines, Where Relevant
	Cite No. <sup>1</sup>	Number	Kind Code <sup>2</sup> (if known)		Cited Document MM-DD-YYYY	Passages or Relevant Figures Appear
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	NON PATENT LITERATURE DOCUMENTS							
Examiner Initials*  Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of								
B1	SHIH, J., et al., "Surface Micromachined and Integrated Capacitive Sensors For Microfluidic Applications", Transducers 2003, USA, pp. 388-391 (2003).							
B2	XIE, J., et al., "Integrated Surface-Micromachined Mass Flow Controller", MEMS 2003, Kyoto, Japan, pp. 20-23 (2003).							
	No. <sup>1</sup> B1	Cite No.1 Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.) date, page(s), volume-issue number(s), publisher, city and/or country where published.  B1 SHIH, J., et al., "Surface Micromachined and Integrated Capacitive Sensors For Microfluidic Applications", Transducers 2003, USA, pp. 388-391 (2003).  B2 XIE, J., et al., "Integrated Surface-Micromachined Mass Flow Controller", MEMS 2003, Kyoto, Japan, pp.						

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## **INFORMATION DISCLOSURE** STATEMENT BY APPLICANT

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Application Number	10/757,973				
Filing Date	January 13, 2004				
First Named Inventor	Xie, Jun				
Art Unit	Unassigned				
Examiner Name	Unassigned				
Attorney Docket Number	020859-002510US				

Document No.  Cite No.  Number Kind  US 5,836,  US 6,033,  US 6,062,  US 6,109,  US 6,124,  US 6,126,	Code <sup>2</sup> (if known) 750 191 256 889 632	Publication Date MM-00-YYYY 11-17-1998 03-07-2000 05-16-2000 08-29-2000	Name of Patentee or Applicant of Cited Document  Cabuz  Kamper et al.  Miller et al.  Zengerte et al.	Pages, Columns, Unes, Where Relevant Passages or Relevant Figures Appear
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INIEO	DALATION	nie	CLOCUDE	Application Number	10/757,973		
			CLOSURE	Filing Date	January 13, 2004		
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				Art Unit	Unassigned		
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Examiner Cite Initials * No.1		Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the ite (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.					
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